



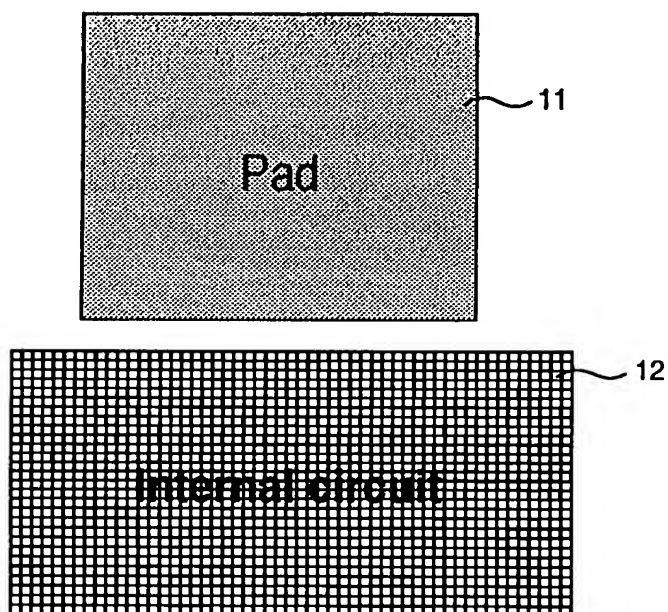
TITLE: "EFFICIENT USE OF WAFER AREA WITH DEVICE UNDER THE PAD APPROACH"

INVENTOR(S): Nian Yang, Hiroyuki Ogawa, Yider Wu, Kuo-Tung Chang, Yu Sun, and Darlene Hamilton

USSN: 10/758,148 Attorney Docket #: AMD-AF01214

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Top side view

(Conventional Art)

Fig. 1

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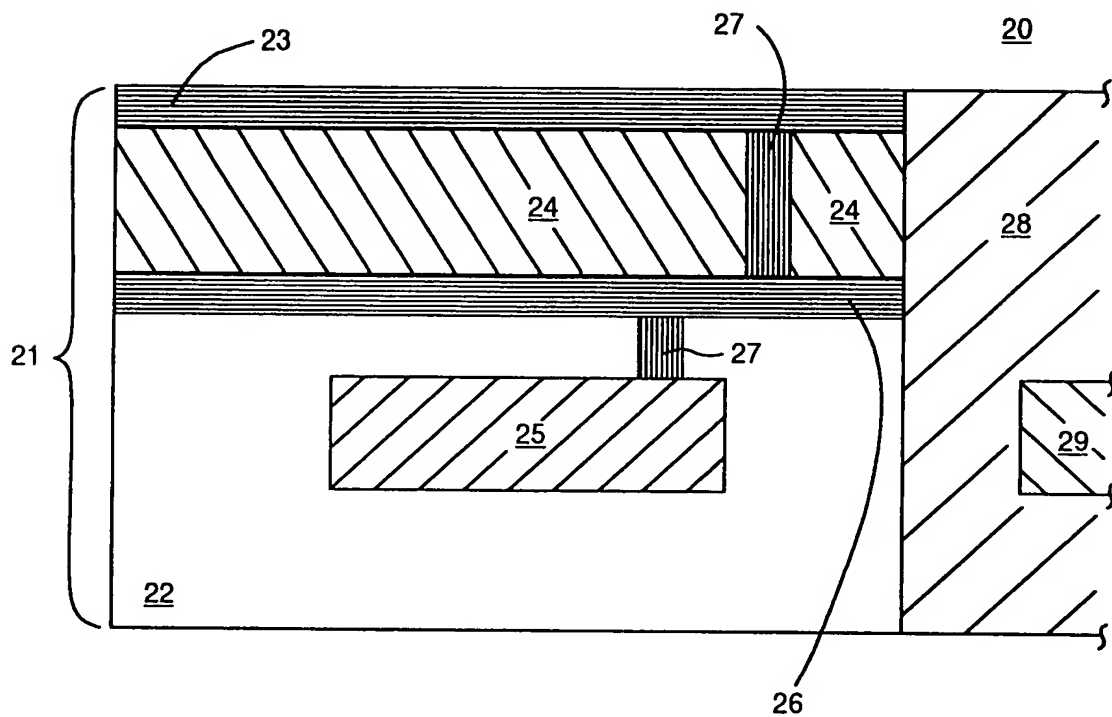
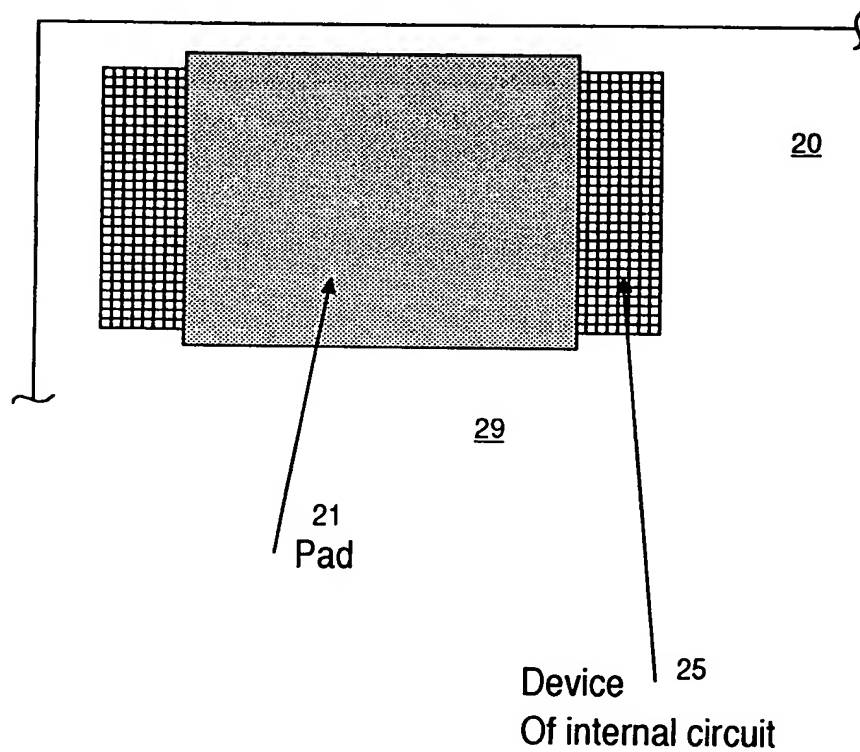


Fig. 2

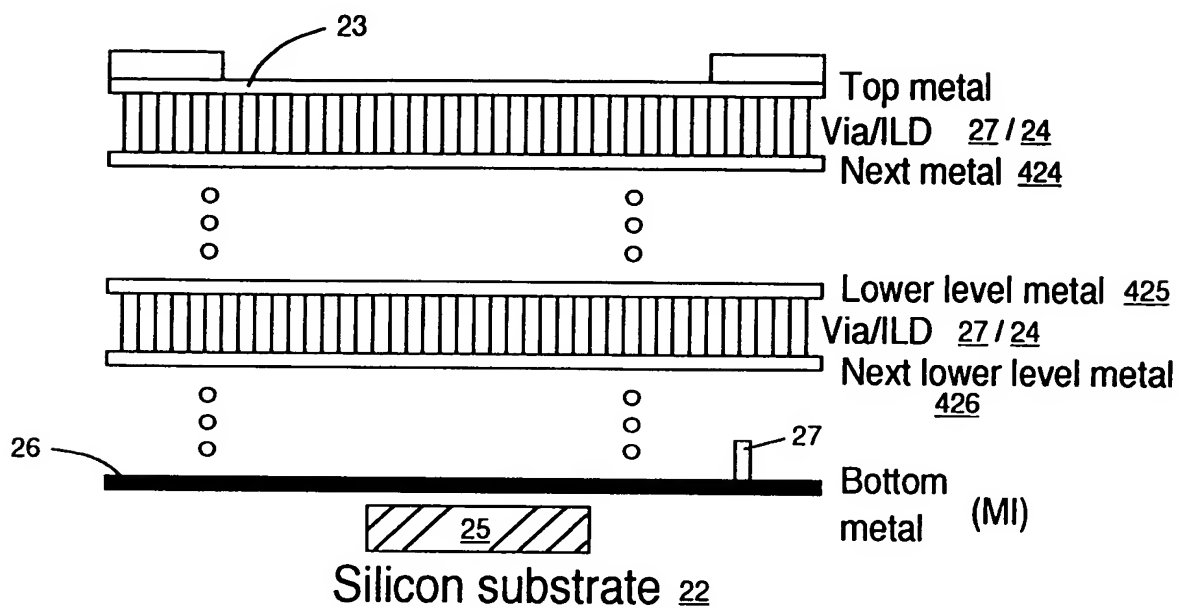
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Top side view

Fig. 3

400



Cross section view

Fig. 4

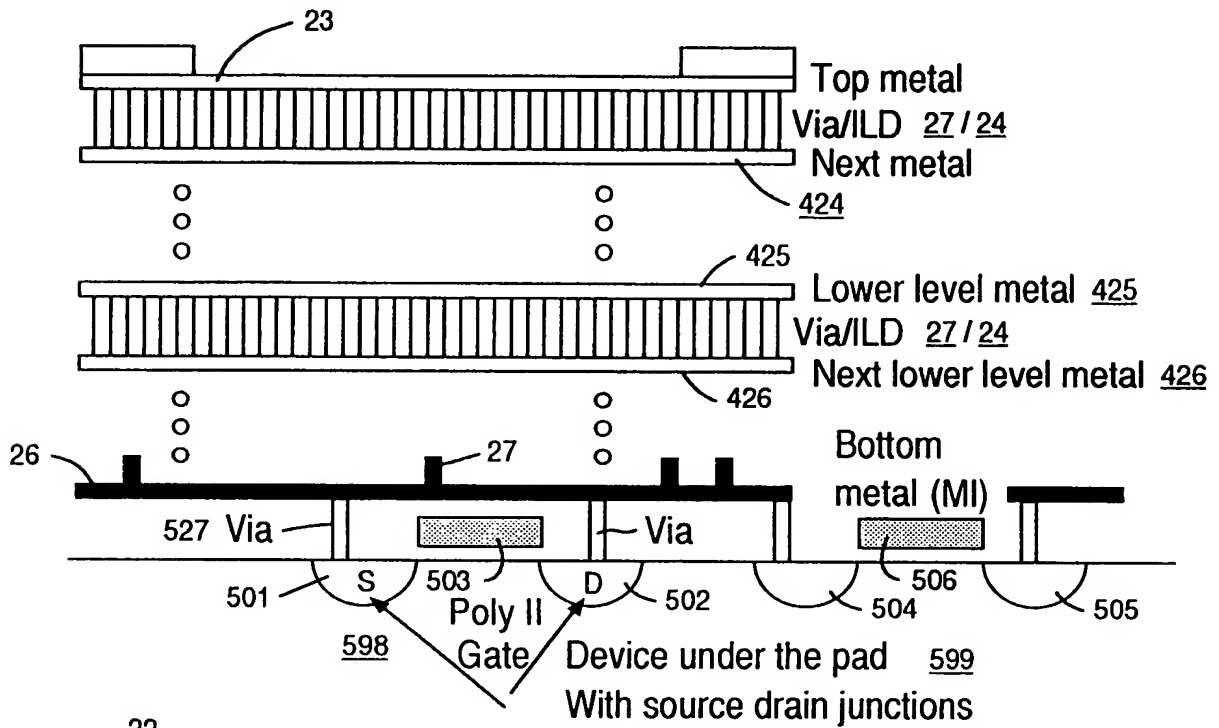
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500



22

Cross section view

Fig. 5

60 Fabricating a Semiconductor Structure

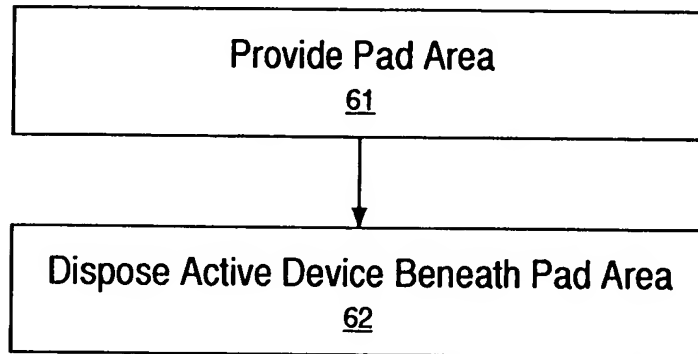


Fig. 6

70

Fabricating a Semiconductor Structure

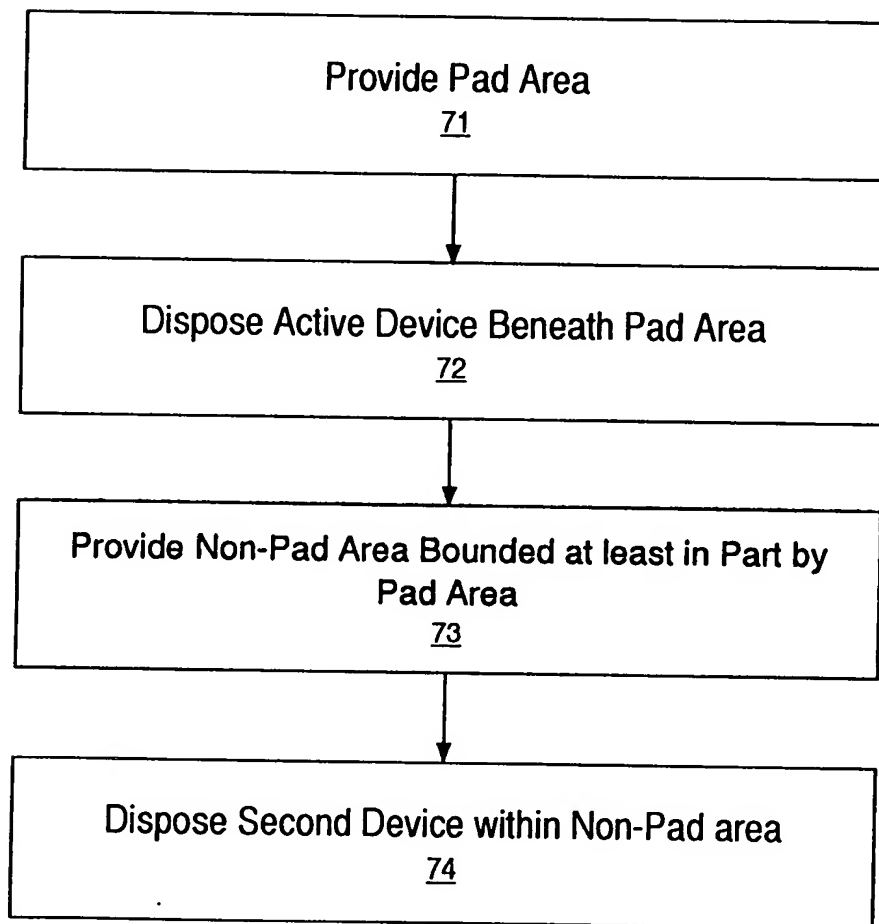


Fig. 7

80

Fabricating a Pad Area

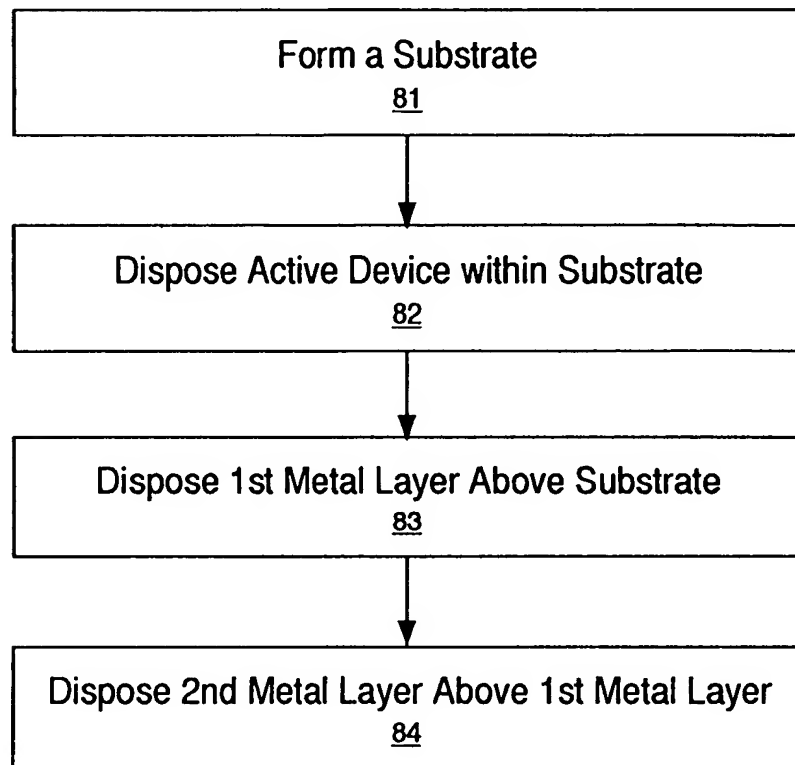


Fig. 8

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90

Fabricating a Pad Area

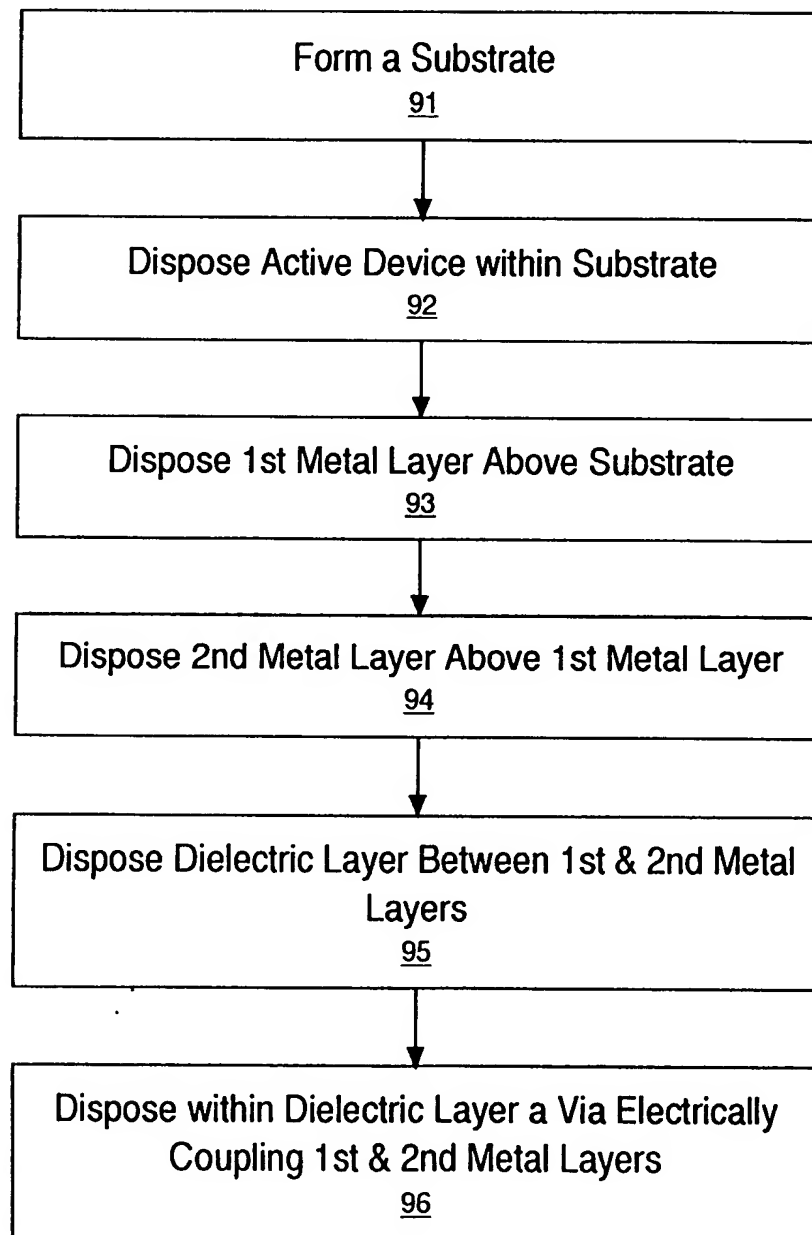


Fig. 9

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100

Fabricating a Pad Area

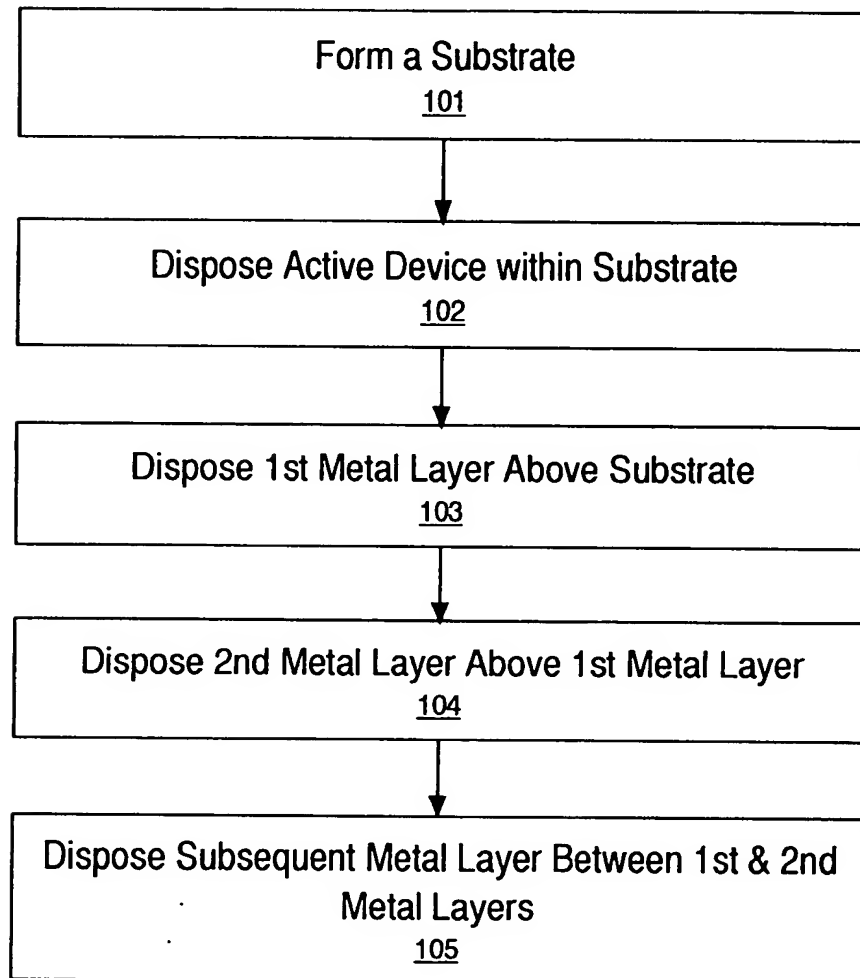


Fig. 10